Improved Automatic Recognition of Engineered Nanoparticles in Scanning Electron Microscopy Images

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Abstract: The amount of engineered nanoparticles produced each year has grown for some time and will grow in the coming years. However, if such particles are inhaled, they can be toxic. Therefore, to ensure the safety of workers, the nanoparticle concentrations at workplaces have to be measured. This is usually done by gathering the particles in the ambient air and then taking images using scanning electron microscopy. The particles in the images are then manually identified and counted. However, this task takes much time. Therefore, we have developed a system to automatically find and classify particles in these images (Kockentiedt et al., 2012). In this paper, we present an improved version of the system with two new classification feature types. The first are Haralick features. The second is a newly developed feature which estimates the counts of electrons detected by the scanning electron microscopy for each particle. In addition, we have added an algorithm to automatically choose the classifier type and parameters. This way, no expert is needed when the user wants to train the system to recognize a previously unknown particle type. The improved system yields much better results for two types of engineered particles and shows comparable results for a third type.

1 INTRODUCTION

Nanoparticles have diameters between 1 nm and 100 nm and are used in all kinds of products such as deodorants or sun cream. These are called engineered nanoparticles as they are intentionally produced rather than being a byproduct of a process such as combustion. However, in addition to having special properties because of their size, they can also be toxic if they are inhaled (Ostrowski et al., 2009). This poses a threat to workers producing or handling such particles. Therefore, there is a need to measure the concentration of engineered nanoparticles in work environments.

So-called particles counters can measure the concentrations of particles of different sizes in the air. However, they cannot distinguish between engineered nanoparticles and other particles, so-called background particles, such as diesel soot, which is common in urban environments (Savolainen et al., 2010). Therefore, particles in the air are gathered using a so-called precipitator and later, images of them are taken using a scanning electron microscope (SEM). By counting the engineered nanoparticles in the images, their concentration in the sampled air can be estimated. This job is typically done by humans. However, counting the particles is very time-consuming. Therefore, we have developed a system to automatically detect and classify particles in SEM images to allow the measurement of the concentration of engineered particles.

In Fig. 1, a few examples of particles in SEM images can be seen. Fig. 1(a) shows a single engineered nanoparticle made of titanium dioxide (TiO2) with a diameter of about 25 nm. However, much more common are so-called agglomerates such as the one in Fig. 1(c), which are multiple nanoparticles sticking together. Both single nanoparticles and agglomerates are called particles. If we specifically want to refer to a single nanoparticle, either as part of an agglomerate or by itself, we will call it primary particle. Fig. 1 also shows very well how similar engineered nanoparticles of a certain size range are to background particles such as diesel soot. Figures 1(a) and 1(b) show primary particles of TiO2 and diesel soot, respectively. Apart form differences in contrast, the images are indistinguishable. Similarly, agglomerates are also very similar as can be seen in Figs. 1(c)
and 1(d). This makes it a challenging classification task because diesel soot is very common in industrial environments.

We want to find the following nanoparticle types:

- Silver (Ag) with an average diameter of 75 nm.
- Titanium dioxide (TiO$_2$) with an average diameter of 25 nm.
- Zinc oxide (ZnO) with an average diameter of 10 nm.

The SEM images we use for this paper each have a size of $4000 \times 3200$. About half of them have a pixel size of 5.1 nm whereas the other ones have a resolution of 1.3 nm per pixel. We assume that the software knows beforehand which type of engineered nanoparticles it has to find and that only this type plus all possible background particle types can occur. This assumption is realistic as there is usually only one type of engineered nanoparticles being produced or processed at a time.

## 2 RELATED WORK

To the best of our knowledge, there are only two other approaches conquering a similar problem on similar particles (Oleshko et al., 1996; Oster, 2010). However, there are several differences to our problem.

Oleshko et al. examine similar nanoparticles to those analyzed by us, but use electron energy loss spectroscopy instead of SEM. They have access to the chemical composition of each agglomerate, which we have not. Apart from that, they only use one feature called fractal dimension, which only gives a single number per agglomerate. Additionally, their aim is to do a characterization of the particles instead of a classification.

Oster, similar to us, classifies nanomaterials on
SEM images. However, instead of trying to find engineered nanoparticles, he is searching for carbon nanotubes. In addition, being a bachelor’s thesis, his work was targeted at samples with a limited set of background particle types, namely diesel soot and quartz dust.

3 METHOD

The system presented in this paper is an improved version of the system we have proposed in (Kockentiedt et al., 2012). Its workflow has three steps: segmentation, feature computation and classification. The first step splits the image into foreground—made up of all particles—and background. In the second step, for each connected component of the foreground, several numerical features are computed. In the classification step, a classifier uses the feature values to assign each connected component to either engineered nanoparticles or background particles. The steps are described in more detail in Sections 3.1 to 3.3.

3.1 Segmentation

In the images available to us, the particles always have a higher intensity than the background. Therefore, our method uses thresholding to separate the particles from the background. We use a method proposed in (Zack et al., 1977) and analyzed in more detail in (Rosin, 2001). It works best because, in contrast to most other thresholding methods, it does not assume that the intensity histogram contains at least two peaks. In our case, a high percentage of the image is covered by background. Therefore, usually only the background distribution is visible in the histogram.

Applying the thresholding to the raw images leads to small holes in the found regions. Therefore, we use a noise removal method proposed by us in (Kockentiedt et al., 2013) before thresholding. It is specifically designed for SEM images and works by first estimating the parameters of the image’s Poisson noise using a statistically derived method. After that, the non-local means image denoising algorithm (Buades et al., 2005) is applied to the image, which has been variance-stabilized using the estimated noise parameters. This approach works better than a Gaussian filter because it preserves the particle contours while removing small holes in the segmentation. Through testing, we have found that a tile count of 8 × 8 works best for the noise estimation. For non-local means, $h = \sqrt{2}$, a neighborhood of $7 \times 7$ and a search window of $21 \times 21$ have shown the best results.

Each connected component of foreground pixels is considered as a particle or agglomerate and is treated as a unit for the feature computation and classification. Connected components smaller than a certain threshold, however, are discarded so that patches of noise are not considered particles. As this threshold, we use 44 pixels. This corresponds to 90% of the average area of the smallest primary particle we want to find in an image with a pixel size of 1.3 nm.

The approach works well to find the particles in an image. However, in images without any particles, patches of the background are recognized as foreground, because a low maximum intensity leads to a threshold which is too small. Therefore, if the highest intensity of a denoised image is lower than 28, it is regarded as empty. This works for all images we have available.

3.2 Feature Computation

After the connected components of the image foreground representing particles and agglomerates have been found, several numerical features are computed for each of them. The task of these features is to capture the properties of a particle in a few numbers in order to make it easier to compare different particles. Thus, similar particles should have similar feature values. The features we use can be categorized into two groups:

- Shape features
- Intensity-based features

They will be explained in the following sections.

3.2.1 Shape Features

We use five basic geometric features:

- The area $A$ of the particle in the image given in nm$^2$.
- The outer contour length $L_O$ of the particle in the image given in nm.
- The total contour length $L_T$ (including contours of holes in the particle) in the image given in nm.
- The isoperimetric quotient $Q_I$ defined as the ratio of the particle’s area $A$ and the area of a circle having a perimeter equal to $L_T$. It is calculated as $Q_I = \frac{4\pi A}{L_T^2}$ and measures the similarity of a particle’s shape to a circle.
- The in-image contour percentage $P_c$ defined as the percentage of the particle’s outer contour which does not touch with the image border.

In addition, we use a more sophisticated feature, which examines the outer contour of a particle using...
wavelets. It works by first expressing the shape of the outer particle contour as a function which maps the length of the contour to its angle. This function is then convoluted using Morlet wavelets of different wavelengths. The mean absolute response to the wavelet of the given wavelength is then used as a feature:

$$W_{\lambda} = \frac{1}{L_0} \int_0^{L_0} \left| \int_{-\infty}^{\infty} \phi^*(l-r)\psi^*_\lambda(l) \, dl \right| \, dl.$$  \hspace{1cm} (1)

Here, $\psi^*_\lambda$ is the real part of a Morlet wavelet with wavelength $\lambda$ and $\phi^*$ is the function expressing the contour shape of the particle. This function shall capture different frequencies of the particle’s contour and, thus, the size distribution of the primary particles of an agglomerate. We compute the feature for the following wavelengths: 5 nm, 10 nm, 20 nm, 50 nm, 100 nm, 200 nm, 500 nm, 1000 nm and 2000 nm. More details on the feature can be found in (Kockentiedt et al., 2012).

### 3.2.2 Intensity-based Features

Our system uses four different types of intensity-based features:

- Maximum intensity.
- Normalized histogram.
- Haralick features.
- Electron count estimates.

The first and simplest feature is the maximum intensity of a particle in the image. The second is a relative intensity histogram of the particle with 10 bins ($h_0, \ldots, h_9$) normalized between the most common background intensity and $i_{\text{max}}$.

In order to use the additional information given by the texture of the particles, we have decided to use Haralick features. This technique is used in several publications on particle detection and classification (Langford et al., 1990; Flores et al., 2003; Laghari, 2003; Rodriguez-Damian et al., 2006; Stachowiak et al., 2008). In fact, it is the only intensity-based feature used in more than one publication examined by us. We have chosen the approach because it is applicable to small and irregularly shaped particles.

Haralick features are derived from the so-called co-occurrence matrix $P_o(i, j)$, $i, j \in I$, where $I$ is the set of possible intensities. $P_o(i, j)$ is defined as the probability that a pair of intensities $i$ and $j$ occurs with the offset $o$. An offset $o = (1, 2)$ would mean that the intensities are 1 pixel apart in the horizontal direction and 2 pixels in the vertical direction.

The entries of the co-occurrence matrix could be used directly as features but assuming 256 intensities, this would amount to 65536 different features per offset. Therefore, several measures derived from the co-occurrence matrix are used instead. We have chosen the set of features used by (Stachowiak et al., 2008) and described in (Stachowiak et al., 2005):

- Contrast:
  $$H_{\text{contrast}, o} = \sum_{i,j \in I} (i-j)^2 P_o(i, j) \hspace{1cm} (2)$$

- Energy:
  $$H_{\text{energy}, o} = P_o^2(i, j) \hspace{1cm} (3)$$

- Entropy:
  $$H_{\text{entropy}, o} = -\sum_{i,j \in I} P_o(i, j) \log_2 P_o(i, j) \hspace{1cm} (4)$$

- Local homogeneity:
  $$H_{\text{hom}, o} = \sum_{i,j \in I} \frac{1}{1 + (i-j)^2} P_o(i, j) \hspace{1cm} (5)$$

- Cluster shade:
  $$H_{\text{shade}, o} = \sum_{i,j \in I} (i-M_{1, o} + j-M_{2, o})^4 P_o(i, j) \hspace{1cm} (6)$$

- Cluster prominence:
  $$H_{\text{prom}, o} = \sum_{i,j \in I} (i-M_{1, o} + j-M_{2, o})^4 P_o(i, j) \hspace{1cm} (7)$$

- Maximum probability:
  $$H_{\text{max}, o} = \max_{i,j \in I} P_o(i, j) \hspace{1cm} (8)$$

where

$$M_{1, o} = \sum_{i,j \in I} i P_o(i, j) \hspace{1cm} (9)$$

$$M_{2, o} = \sum_{i,j \in I} j P_o(i, j). \hspace{1cm} (10)$$

We compute these features for the following offsets in order to capture different directions and distances: $(1, 0)$, $(0, 1)$, $(1, 1)$, $(1, -1)$, $(5, 0)$, $(0, 5)$, $(10, 0)$, $(0, 10)$, $(10, 0)$, $(0, 10)$.

The last set of features is a completely new one. It tries to estimate the number of electrons which has been detected by the SEM for each pixel of a particle. SEMs shoot an electron beam at the specimen and detect so-called secondary electrons which are emitted from the sample. The intensity of a pixel represents the number of electrons detected at the corresponding position. However, there is no one-to-one relationship between electron count and intensity because the operator has to adjust the brightness and contrast settings in order to increase the contrast while avoiding intensity clipping. The relationship is as follows:

$$i = aC + b, \hspace{1cm} (11)$$
where \(C\) is the electron count, \(i\) is the intensity and \(a\) and \(b\) correspond to the contrast and brightness settings, respectively. Therefore, comparing the intensities directly can sometimes be misleading.

In (Kockentiedt et al., 2013), we have proposed a method to estimate the parameters of the Poisson noise of SEM images. As a side effect, the method also estimates the values of the parameters \(a\) and \(b\). This allows us for each pixel of the image to estimate the number of electrons detected at the corresponding point of the sample. Thus, we can compute each particle’s minimum (\(C_{\text{min}}\)), mean (\(C_{\text{mean}}\)) and maximum (\(C_{\text{max}}\)) electron count and use these values as features.

### 3.3 Classification

Using the feature values of each particle, a classifier decides, which class it belongs to. We use the classifier implementations of the data mining software Weka (Hall et al., 2009). As we do not know the distribution of the feature values, we have chosen to use a geometric classification approach using a decision boundary (Jain et al., 2000). Because the feature count is high and the number of training samples is relatively low, we have chosen a simple classifier, namely logistic regression, to counteract overfitting.

The training images have been created so that only particles of one specific type are visible on each image in order to avoid mislabeled training particles.

The system shall be able to learn to recognize previously unknown types of engineered nanoparticles. However, choosing the best classification parameters can usually only be done by an expert in the field of machine learning. Therefore, we have developed an algorithm which automatically tests different parameters from a previously defined set to find the best combination for a new particle type using cross-validation. It uses a genetic algorithm where each parameter combination is treated as a solution and their fitness is evaluated using their classification performance estimated using cross-validation. First, 20 random configurations are tested. Then, out of this population of 20, two solutions are combined and randomly altered to generate a new solution. If it performs better than the worst solution of the current population, the new solution takes its place in the population. This process is repeated until a certain time is exceeded. Then, the classifier is trained on all samples using the best parameter combination.

The genetic algorithm can alter the following parameters:

- **Used features:** The algorithm can perform feature selection in order to reduce overfitting. (Possible values: Any subset of features)
- **Weight of the engineered particles:** The genetic algorithm can choose to give the engineered nanoparticles a higher weight than the background particles. This way, misclassified engineered particles are regarded as worse than misclassified background particles. The weighting may be necessary because there are much fewer engineered particles than background particles in our dataset. (Possible values: 1, 3, 10, 30, 100)
- **Ridge parameter:** The genetic algorithm is able to choose the ridge parameter of the logistic regression. A high value can avoid overfitting. (Possible values: 0, 1, 1, 10)

### 4 EVALUATION AND RESULTS

We have used an extended version of the test dataset used in (Kockentiedt et al., 2012). It contains 174 SEM images with 13649 particles/agglomerates. Table 1 is a detailed listing of the types of particles. We have tested our system on the dataset and evaluated the classification performance using 10-fold cross-validation, where the parameter selection algorithm has been able to run for 2 hours in each fold. Probably the most commonly used measure to do this is accuracy, which is defined as the percentage of correctly classified particles. However, in cases where one class is much rarer than another, accuracy is a bad choice. For example, in case of Ag in our dataset, the ratio of engineered particles to background particles is 97:10943. A dysfunctional classifier that classifies every sample as a background particle would reach a really good accuracy of 99%.

Instead, Sun et al. (Sun et al., 2009) suggest F-measure and G-mean as measures to use in case of
class imbalance. We have chosen G-mean as it normally doesn’t change if the ratio between the classes changes because it only relies on the true positive rate and the true negative rate. G-mean is defined as follows (Kubat et al., 1998):

\[ G = \sqrt{TP_r \cdot TN_r}, \]  

(12)

where \( TP_r \) and \( TN_r \) are the true positive and the true negative rate, respectively.

Table 2 shows the results of the classification compared to those achieved in (Kockentiedt et al., 2012). For TiO\(_2\) and ZnO, the improved system shows much better results. This shows that the new components add value to the system. For Ag, the results have slightly deteriorated. We believe, this has several reasons:

- The Ag agglomerates added to the original dataset contain samples which look different than other Ag agglomerates in that they have a much lower intensity. These particles may be a contamination and may be composed of a different material. However, we are not able to tell because, as noted before, our data has no information on the composition of the particles.
- In (Kockentiedt et al., 2012), the selection of the classifier parameters and the feature selection has been done on the whole dataset. In contrast, for this paper, for each cross-validation fold, the automatic parameter selection and feature selection has been done only on the training set. This is a more correct approach, but it can lead to worse results.
- For the results presented in this paper, the automatic parameter and feature selection method has had 2h time in each case. To achieve the results in (Kockentiedt et al., 2012), the feature selection alone ran overnight. That time did not include the selection of the classifier parameters as it was manually done beforehand.

For each of the three particle types, we have performed a 10-fold cross-validation. This means that 30 classifiers have been trained using 30 separate feature subsets. Thus, for a given feature, we can look at the number of classifiers which have been trained with it. If that number is close to 30, we can assume that the feature is vital to differentiate the given particles classes. If it is close to 0, the feature can probably be left out without affecting the classification performance too much. The average number of classifiers trained using a given feature is 17.9. Table 3 lists the ten most used features in our experiments. The estimated maximum electron count \( C_{\text{max}} \) has been used in all but one feature sets. The second most used feature is the estimated minimum electron count \( C_{\text{min}} \). In addition, \( C_{\text{mean}} \) was used by 20 classifiers, which is still above average. This shows that the electron count estimation adds substantial value to the system. As a comparison, the maximum intensity \( I_{\text{max}} \) has only been used in 17 feature subsets, which is considerably less than the 29 of the estimated maximum electron count \( C_{\text{max}} \). This supports our previously stated assumption that the absolute image intensity carries little information in itself. The electron estimation developed by us extracts the important information and makes it available to the classifier.

Six of the ten most used features belong to the Haralick features. This suggests that they also play an important role in the distinction of the particle classes. In addition, these six features stem from five different Haralick feature types. This leads us to believe that each of the used Haralick feature types is important and that it would not be enough to use a single feature type.

Table 3: The ten most used features. The count value indicates how many of all 30 classifiers have been trained using the given feature.

<table>
<thead>
<tr>
<th>Rank</th>
<th>Count</th>
<th>Feature</th>
</tr>
</thead>
<tbody>
<tr>
<td>1</td>
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<td>( C_{\text{max}} )</td>
</tr>
<tr>
<td>2</td>
<td>25</td>
<td>( C_{\text{min}} )</td>
</tr>
<tr>
<td>3</td>
<td>24</td>
<td>( H_{\text{contrast}} ), (1.1)</td>
</tr>
<tr>
<td>4</td>
<td>23</td>
<td>( H_{\text{entropy}} ), (0.10)</td>
</tr>
<tr>
<td>5</td>
<td>23</td>
<td>( H_{\text{hom}} ), (20.0)</td>
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<tr>
<td>6</td>
<td>23</td>
<td>( W_{1000} )</td>
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<tr>
<td>7</td>
<td>22</td>
<td>( H_{\text{contrast}} ), (1.0)</td>
</tr>
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<td>22</td>
<td>( H_{\text{max}} ), (1.0)</td>
</tr>
<tr>
<td>9</td>
<td>22</td>
<td>( H_{\text{prom}} ), (0.10)</td>
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<tr>
<td>10</td>
<td>22</td>
<td>( W_{200} )</td>
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</table>
5 CONCLUSION

We have improved the system to detect and recognize engineered nanoparticles we proposed in (Kockentiedt et al., 2012). We have added an appropriate filter to the image segmentation and reviewed its parameters. Moreover, we have added two types of classification features: Haralick features and estimated electron counts. We have shown that they add considerable value to the system by testing how often these features have been selected for the training of the classifier. In addition, we have introduced an algorithm to automatically select the best classification parameters and features. This way, even inexperienced users can train the system to recognize new particle types without setting any parameters. The improved system achieves much better results than the original one for two engineered nanoparticle types and comparable results for a third type.

In the future, we want to further improve the usability of the system and reduce the amount of manual work. Firstly, we want to reduce the number of samples that have to be manually classified by automatically selecting the best candidates to be classified. This approach is called active learning.

Secondly, we want to allow the system to predict the classification performance to be expected if more training samples are added. This way, the user can make an informed decision if it is worth spending time to make more SEM images to generate more training samples. If the classification performance is unlikely to be significantly improved, the user can save time and money which would otherwise have been spent. Early results of this are reported in (Kockentiedt et al., 2014).

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